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EP3910401 - OPTICAL BEAM INTENSITY CONTROL SYSTEM WITH PIEZOELECTRIC ACTUATOR [Right-click to bookmark this link]	
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	[2021/46]
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Extension states	BA	Not yet paid
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Title	German:	STEUERSYSTEM FÜR DIE INTENSITÄT EINES OPTISCHEN STRAHLS MIT PIEZOELEKTRISCHEM AKTUATOR [2021/46]
	English:	OPTICAL BEAM INTENSITY CONTROL SYSTEM WITH PIEZOELECTRIC ACTUATOR [2021/46]
	French:	SYSTÈME DE CONTRÔLE DE L'INTENSITÉ DU FAISCEAU OPTIQUE AVEC ACTIONNEUR PIÉZOÉLECTRIQUE [2021/46]
Examination procedure	11.11.2021	Examination requested [2021/51]
	11.11.2021	Date on which the examining division has become responsible
	01.04.2022	Communication of intention to grant the patent
Documents cited:	Search	[A]JP2003329941 (SEIKO INSTR INC) [A] 1-6 * paragraphs [0011] - [0020]; figures 1-7 *;
		[A]EP1453116 (SEIKO EPSON CORP [JP]) [A] 1-6 * paragraphs [0073] - [0091]; figures 1-9 *;
		[A]US4210837 (MISIKOV VITALY M [SU], et al) [A] 1-6 * column 3, line 47 - column 4, line 21; figures 1-5 *;
		[A] - VASILJEV P ET AL, "The investigation of the flat ring-type radial-torsional ultrasonic actuator and its application in micro UAV's", INTERNATIONAL WORKSHOP ON PIEZOELECTRIC MATERIALS AND APPLICATIONS IN ACTUATORS 2019, 1-4 OCTOBER 2019, LYON, (20191001), pages 161 - 162, XP009525970 [A] 1-6 * section II; figures 1, 2 *
	by applicant	US7706069

[US8203253](#)